

(Rev. 2-32) PATENT AND TRADEMARK OFFICE
CHEMICAL-ORGANIC PLANARIZATION PROCESS FOR
ATOMICALLY SMOOTH INTERFACES

ATTY. DOCKET NO.	SERIAL NO.
0937.0017	09 902 408

INFORMATION DISCLOSURE

STATEMENT BY APPLICANT

(Use several sheets if necessary)

APPLICANT

Gerald T. Mearini and Laszlo Takacs

FILING DATE

July 10, 2001

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U.S. PATENT DOCUMENTS

EXAMINER INITIAL	DOCUMENT NUMBER							DATE	NAME	CLASS	SUB- CLASS	FILING DATE IF APPROPRIATE
RRB	5	7	4	8	3	5	0	5/5/98	Pan et al	359	130	6/19/96
↑	6	2	0	5	2	7	0	3/20/01	Cao	385	24	9/23/99
	6	2	3	3	2	6	1	5/15/01	Mesh et al	372	32	6/9/99
	5	5	2	9	6	7	1	6/25/96	Debley et al.	204	192.34	7/27/94
	5	7	2	5	4	1	3	3/10/98	Malshe et al	451	41	5/6/94
	4	7	4	7	9	2	2	5/31/88	Sharp	204	192.11	3/25/86

FOREIGN PATENT DOCUMENTS

		DOCUMENT NUMBER	DATE	COUNTRY	CLAS S	SUB- CLAS S	TRANSLATIO N YES NO

OTHER DOCUMENTS (Including Author, Title, Date, Pertinent Pages, Etc.)

		Kumar, et al.; <i>Near-Infrared Bandpass Filter from Si/SiO₂; Multilayer Coatings</i> ; February 1999
		Suntola, T.; <i>Cost-Effective Processing by Atomic Layer Epitaxy</i> ; 1993
		Bachman, et al.; <i>Molecular Layer Epitaxy by Real-Time Optical Process Monitoring</i> ; Department of Materials Science and Engineering, North Carolina State University, 1997.
		H., Kawai, T. Tabata; <i>Atomic Layer Control of the Growth of Oxide Superconductors Using Laser Molecular Beam Epitaxy</i> ; 1997.
		Spiller, E; <i>Smoothing of Multilayer X-Ray Mirrors by Ion Polishing</i> ; IBM Research Division, Thomas J. Watson; 1993.
		Puik, E.J., van der Wiel and Zeijlemaker, H, and Verhoeven, J.; <i>Ion Etching of Thin W Layers: Enhancing Reflectivity of W-C Multilayer Coatings</i> ; March 30, 1989.
		Nishizawa, J., Abe, H., and Kurabayashi, T.J. 132(5) (1985).
		Puik, E.J., et al.; <i>Appln. Surf. Sci. 47 (1991) 251.</i>
RRB		Kloidt, A, et al.; <i>Thin Sol Films</i> , 228 (1993) 154.

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RRB	Imai, F., Kunimori, K., and Nozoye, H; <i>Novel Epitaxial Growth Mechanism of Magnesium Oxide/Titanium Oxide Ceramics Superlattice Thin Films Observed by Reflection High-Energy Electron Diffraction</i> ; November 8, 1993.
RRB	Kildemo, et al.; <i>Real Time Control of the Growth of Silicon Alloy Multilayers by Multiwavelength Ellipsometry</i> ; 1996.

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